

## U.S. Department of Commerce, Patent and Trademark Office

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First Named Inventor: Weidong Yang

Group Art Unit: Unknown

Examiner Name: Unknown

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Attorney Docket No.: NAN066 US

## INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use several sheets if necessary)



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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	1.	5,214,492	25-May-93	LoBianco et al.	356	400	8/2/1991
	2.	5,216,257	Jun. 1, 1993	Brueck et al.	250	548	7/9/1990
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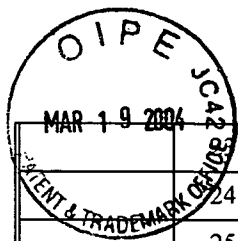
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	20.	WO 01/84382 A1	Nov. 8, 2001	PCT	G06F	17/50	5/4/2000	
	21.	WO 02/065545 A2	Aug. 22, 2002	PCT	H01L	21/66	2/12/2001	
	22.	WO 02/069390 A2	Sep. 6, 2002	PCT	H01L	21/66	2/27/2001	

Examiner

Date Considered

\*EXAMINER: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /D.R./



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